

Sensitive detection of process gas contaminants and safety hazards Measurements made easy

Monitoring in semiconductor fabrication facilities and other, nonhazardous locations, LGR-ICOS[™] 927 series laser process analyzers measure trace gas contaminants with unprecedented accuracy and sensitivity.

- No consumables, columns, carrier gases, liquids or pre-scrubbers
- Simple sample conditioning reduces system complexity and cost
- Significantly higher sensitivity, accuracy, precision and faster response time enables improved process and quality control
- Field calibration is not required. Single span gas verification only
- Field serviceable & modular design virtually eliminates return-to-factory repair

